

Gas treatment system comprising a monitoring unit

Abstract

The present invention relates to a gas treatment system (2) comprising at least one first line (10) in which a gas in the vapour state circulates, and a second line (40) in which gas in the liquid state at least partially circulates, the first line (10) comprising at least one compression device (20), the second line (40) comprising at least one pumping member (42) which is configured to supply the second line (40) with gas in the liquid state, characterised in that the gas treatment system (2) comprises a monitoring unit (44) which controls the operation of the pumping member (42) according to at least one temperature of the gas in the vapour state that is determined at the inlet of the compression device (20).

Figure 1